

L Number	Hits	Search Text	DB	Time stamp
32	30	(microprobe near4 (assembly system apparatus device machine mechan\$4)).ti.	USPAT; US-PGPUB; EPO; JPO	2003/11/15 23:45
33	45	(microprobe near4 (assembly system apparatus device machine mechan\$4)).clm.	USPAT; US-PGPUB; EPO; JPO	2003/11/15 23:49
34	6	((microprobe near4 (assembly system apparatus device machine mechan\$4)).clm.) and cantilever	USPAT; US-PGPUB; EPO; JPO	2003/11/15 23:41
35	3	("5052505" "4724318" "4883959").pn.	USPAT; US-PGPUB; EPO; JPO	2003/11/15 23:41
36	1523	((("AFM" microcantilever cantilever beam "force detector" "force sensor") and ((static strain stress) near3 (deflection deflect))))	USPAT; US-PGPUB; EPO; JPO	2003/11/15 23:50
37	219	(microprobe near4 (assembly system apparatus device machine mechan\$4))	USPAT; US-PGPUB; EPO; JPO	2003/11/15 23:49
38	1	((microprobe near4 (assembly system apparatus device machine mechan\$4))) and (((("AFM" microcantilever cantilever beam "force detector" "force sensor") and ((static strain stress) near3 (deflection deflect))))	USPAT; US-PGPUB; EPO; JPO	2003/11/15 23:49
39	314	((("AFM" microcantilever cantilever beam "force detector" "force sensor") near6 ((static strain stress) near3 (deflection deflect))))	USPAT; US-PGPUB; EPO; JPO	2003/11/16 00:36
40	40	((("AFM" microcantilever cantilever beam "force detector" "force sensor") near6 ((static strain stress) near3 (deflection deflect))).clm.	USPAT; US-PGPUB; EPO; JPO	2003/11/16 00:05
41	16	((("AFM" microcantilever cantilever beam "force detector" "force sensor") near6 ((static strain stress) near3 (deflection deflect))).clm.) and 73/\$.ccls.	USPAT; US-PGPUB; EPO; JPO	2003/11/16 00:27
42	1		USPAT	2003/11/16 00:11
43	1		USPAT	2003/11/16 00:11
44	1		USPAT	2003/11/16 00:19
45	1		USPAT	2003/11/16 00:23
46	1		USPAT	2003/11/16 00:26
47	1	6189374.pn.	USPAT; US-PGPUB; EPO; JPO	2003/11/16 00:28
48	8	((("AFM" microcantilever cantilever beam "force detector" "force sensor") near6 ((static strain stress) near3 (deflection deflect)))) and (angle near3 (compensat\$4 correct\$5))	USPAT; US-PGPUB; EPO; JPO	2003/11/16 00:44
49	22	((("AFM" microcantilever cantilever beam "force detector" "force sensor") near6 ((static strain stress) near3 (deflection deflect)))) and ((angle near3 (compensat\$4 correct\$5)) wedge)	USPAT; US-PGPUB; EPO; JPO	2003/11/16 00:44